

Application/Control No.	Applicant(s)/Patent under Reexamination	
09/447,052	SUEHIRA, SEISHI	
Examiner	Art Unit	
Chau Nguyen	2176	

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SEARCHED					
Class	Subclass	Date	Examiner		
715	513	3/29/2006	CN		
715	522	3/29/2006	CN		
715	523	3/29/2006	CN		
715	513	9/27/2006	CN		
715	522-523	09/27/2006	CN		
715	515	9/28/2006	CN		
707	200	9/28/2006	CN		
707	203	9/28/2006	CN		
707	204	9/28/2006	CN		

INTERFERENCE SEARCHED					
Class	Subclass	Date	Examiner		
715	513	5/11/2007	CN		
715	522	5/11/2007	CN		
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SEARCH NO (INCLUDING SEARCH		)
	DATE	EXMR
Updated Search on East Reports	3/29/2006	CN
NPL Search on IEEE Database	3/30/2006	CN
Updated Search on East Reports	9/27/2006	CN
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